



AF/2800

[10191/1565]

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants : Volker BECKER et al.
Serial No. : 09/674,984
Filed : January 8, 2001
For : A DEVICE AND METHOD FOR DETERMINING THE
LATERAL UNDERCUT OF A STRUCTURED SURFACE
LAYER

Examiner : William D. Coleman
Group Art Unit : 2823

Commissioner for Patents
Washington, D.C. 20231

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AMENDMENT AFTER FINAL OFFICE ACTION UNDER § 1.116

SIR:

In response to the final Office Action mailed October 21, 2002, please amend the above-identified application as set forth below. Entry of the amendment is respectfully requested since the amendment raises no new issues and puts the rejected claims in condition for allowance and/or in better form for appeal.

IN THE CLAIMS:

Please amend claims 23 as follows:

23. (Twice Amended) A device for determining an extent of an at least locally etched lateral undercut of a structured surface layer on a sacrificial layer, comprising:
at least one passive electronic component arranged on the structured surface layer and in the shape of a coil for determining a physical measured quantity that is proportional to the extent of the etched lateral undercut.